

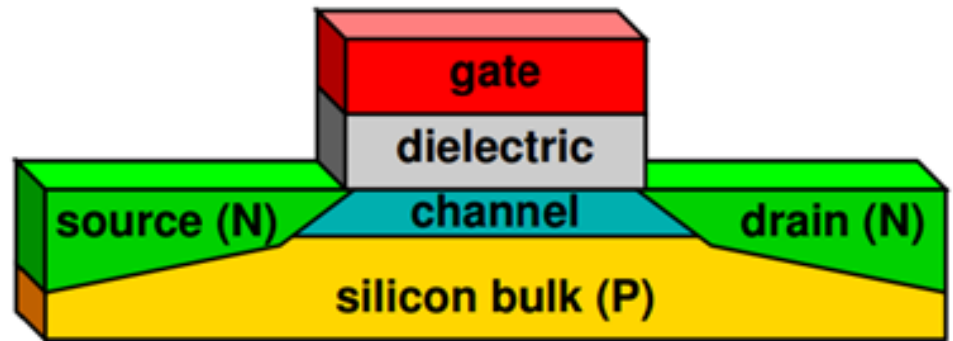
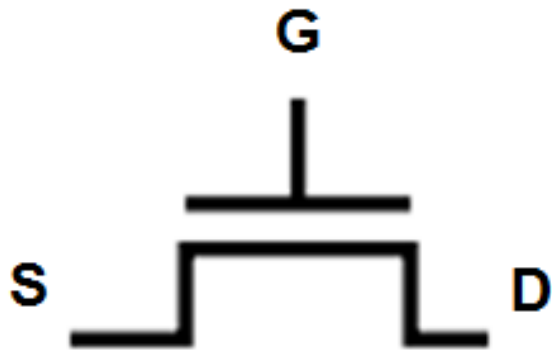
EECS 312 Discussion 12

Review 1

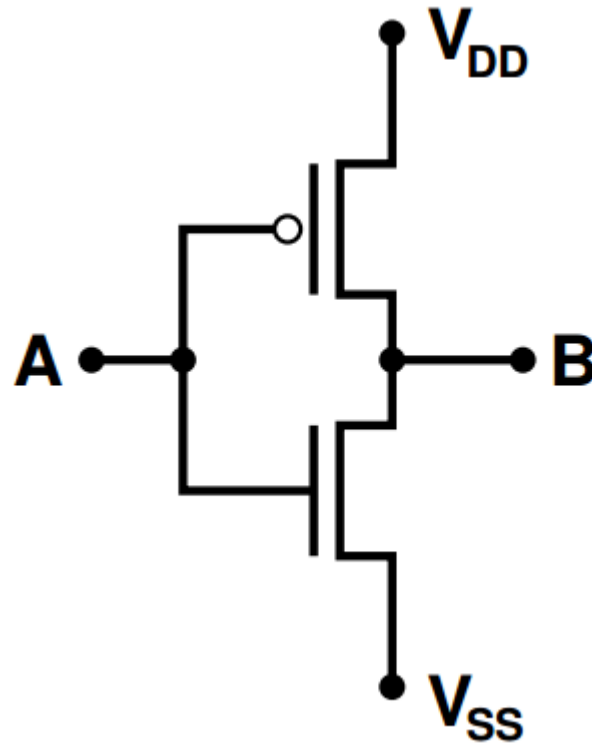
11/22

Shengshuo Lu
(luss@umich.edu)

NMOS



Logic Gates

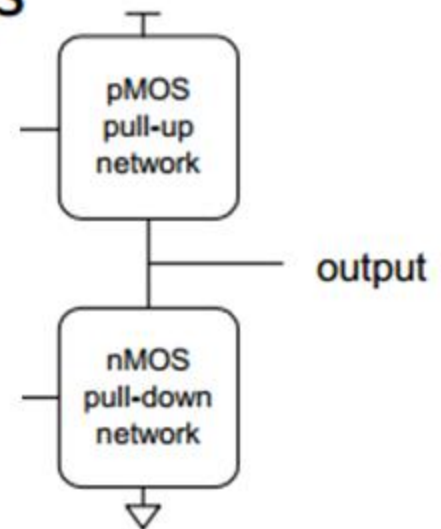


Inverter

Complementary CMOS

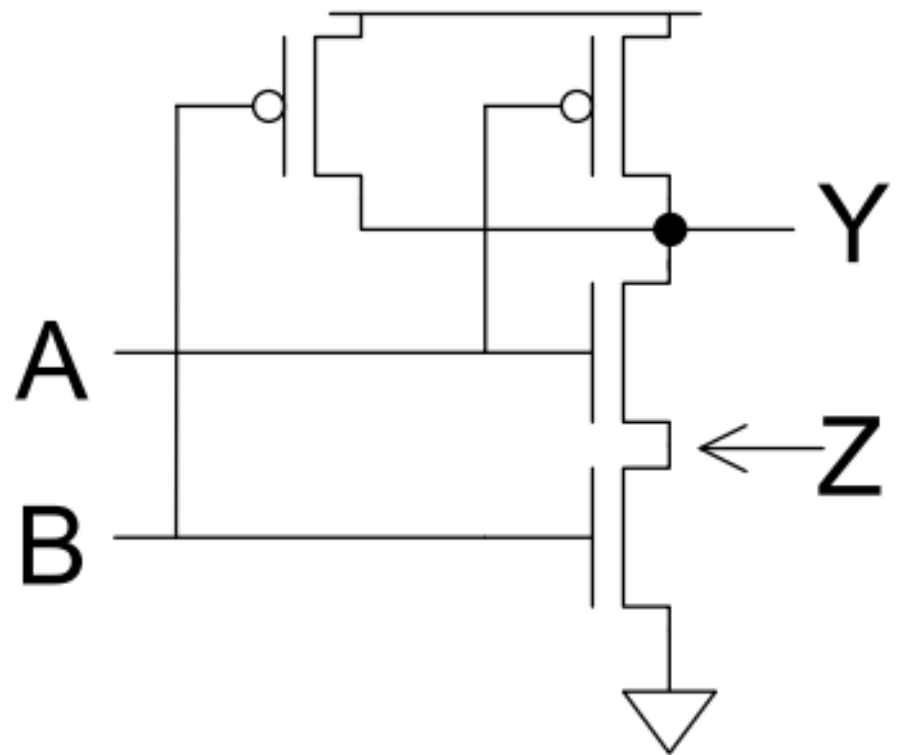
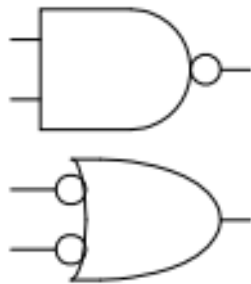
- Complementary CMOS logic gates
 - nMOS *pull-down network*
 - pMOS *pull-up network*
 - Also called static CMOS

	Pull-up OFF	Pull-up ON
Pull-down OFF	Z (float)	1
Pull-down ON	0	X (crowbar)



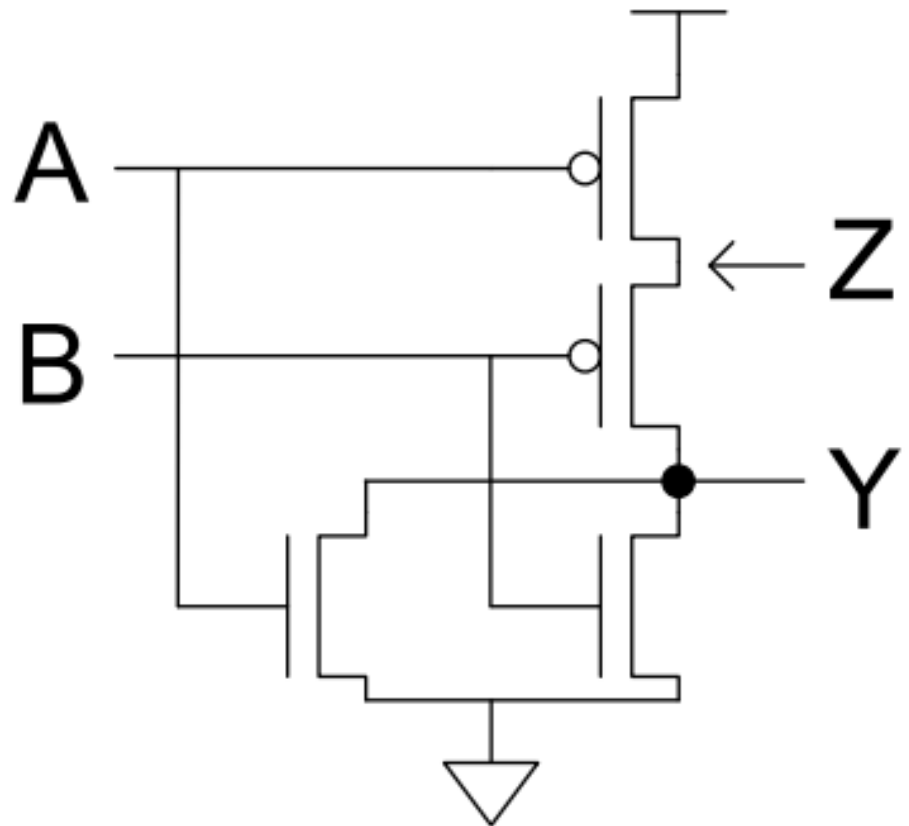
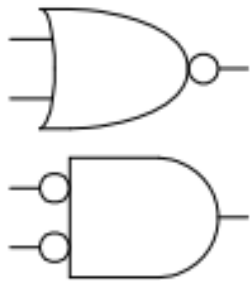
CMOS NAND Gate

A	B	Y	Z
0	0	1	$\sim 100\text{mV}$
0	1	1	0
1	0	1	$V_{DD} - V_{th}$
1	1	0	0



CMOS NOR Gate

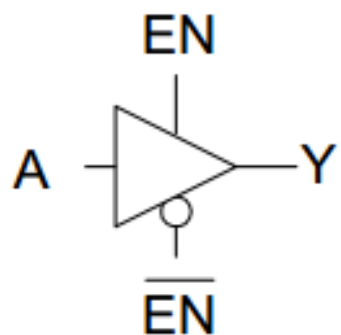
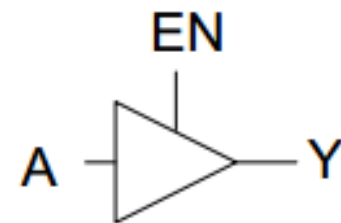
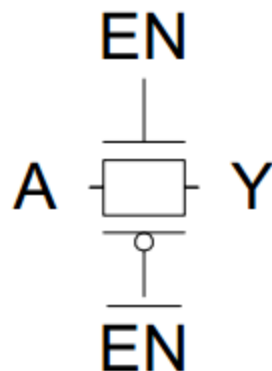
A	B	Y	Z
0	0	1	1
0	1	0	1
1	0	0	V_{th}
1	1	0	$\sim V_{DD}-100mV$



Tristates

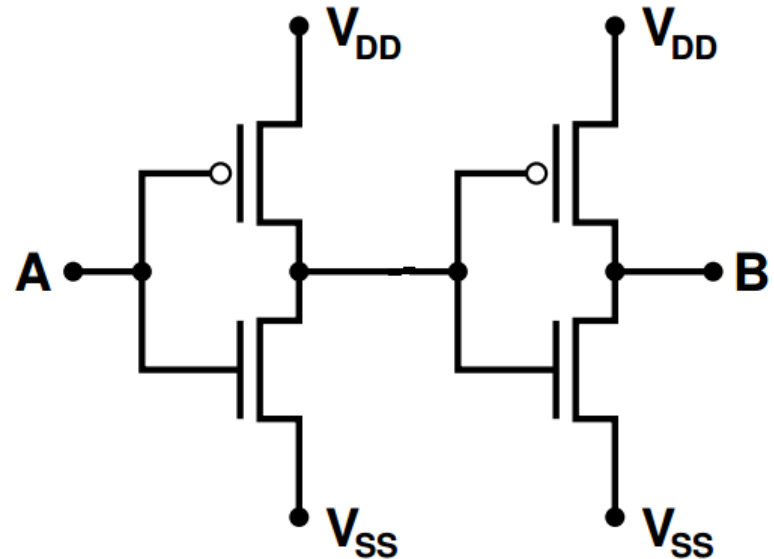
- *Tristate buffer* produces Z when not enabled

EN	A	Y
0	0	Z
0	1	Z
1	0	0
1	1	1



Power

- Dynamic Power
- Static Power
- Short-Circuit Power *



Power

$$P = P_{SWITCH} + P_{SHORT} + P_{LEAK}$$

$$P_{SWITCH} = C \cdot V_{DD}^2 \cdot f \cdot A$$

$$\frac{1}{2} f C V_{dd}^2$$

$$\dagger P_{SHORT} = \frac{b}{12} (V_{DD} - 2 \cdot V_T)^3 \cdot f \cdot A \cdot t$$

$$P_{LEAK} = V_{DD} \cdot (I_{SUB} + I_{GATE} + I_{JUNCTION} + I_{GIDL})$$

C : total switched capacitance

V_{DD} : high voltage

f : switching frequency

A : switching activity

b : MOS transistor gain

V_T : threshold voltage

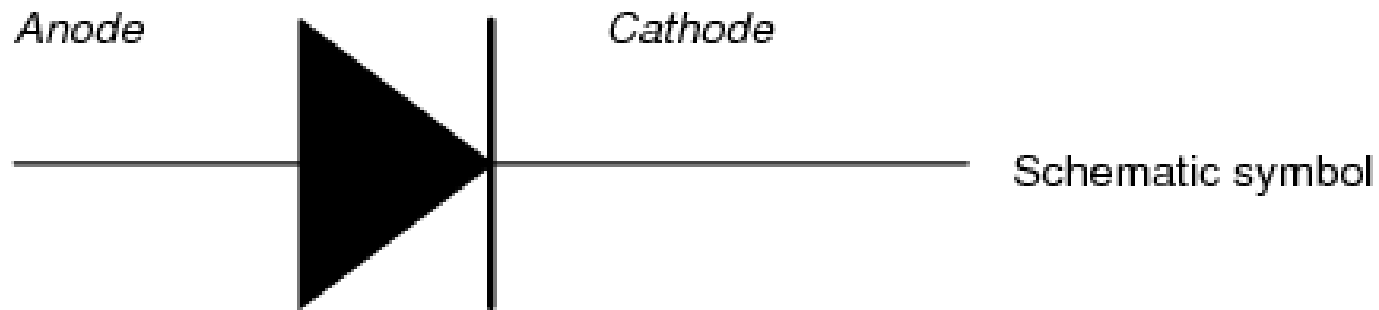
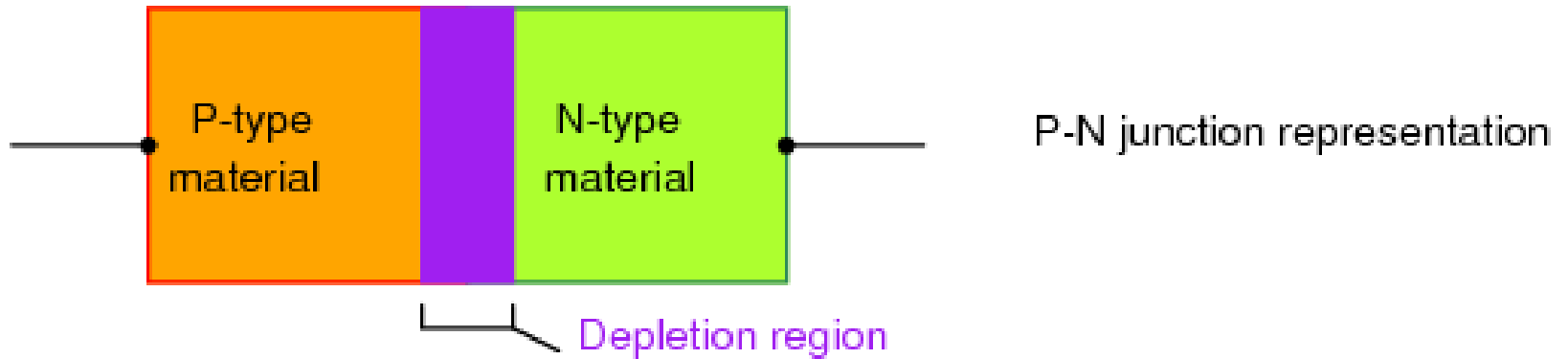
t : rise/fall time of inputs

$\dagger P_{SHORT}$ usually $\leq 10\%$ of P_{SWITCH}

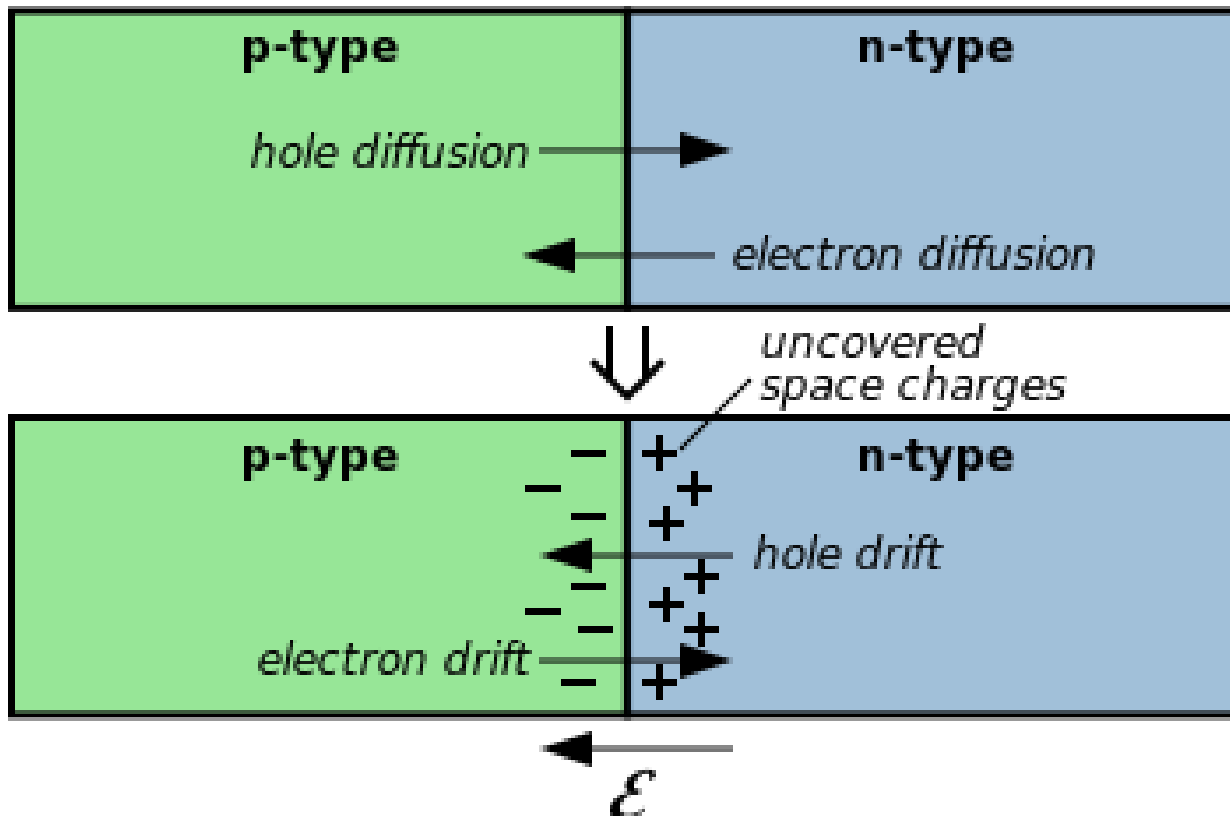
Smaller as $V_{DD} \rightarrow V_T$

$A < 0.5$ for combinational nodes, 1 for clocked nodes.

Diode

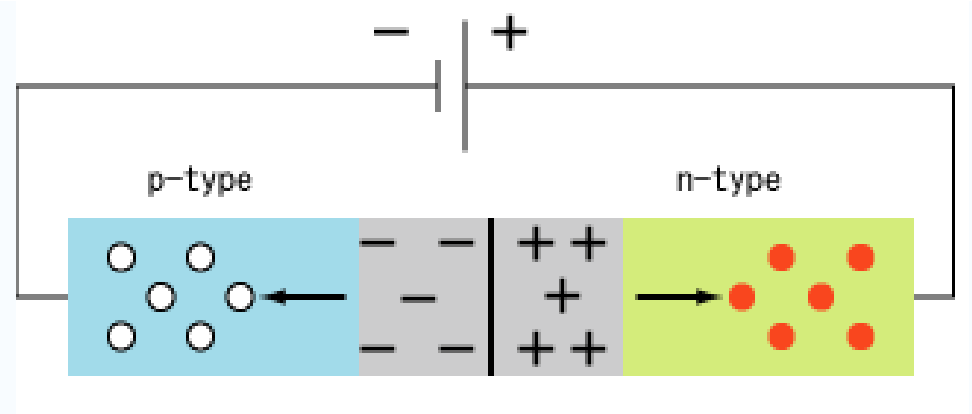


Diode

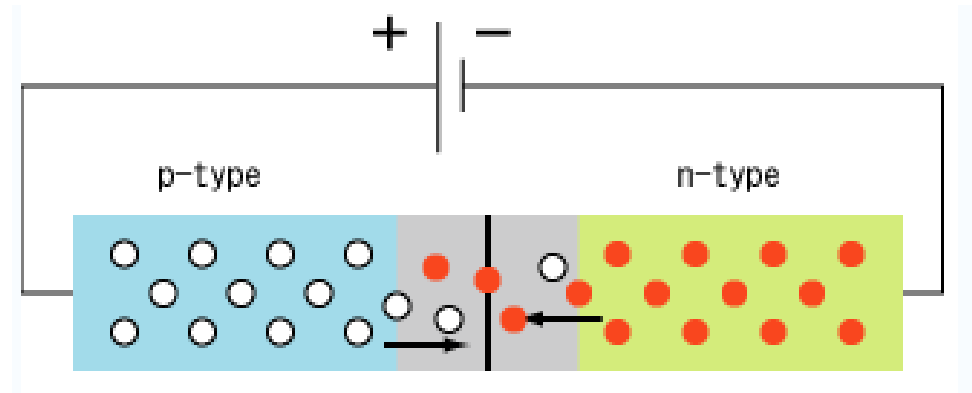


Diode

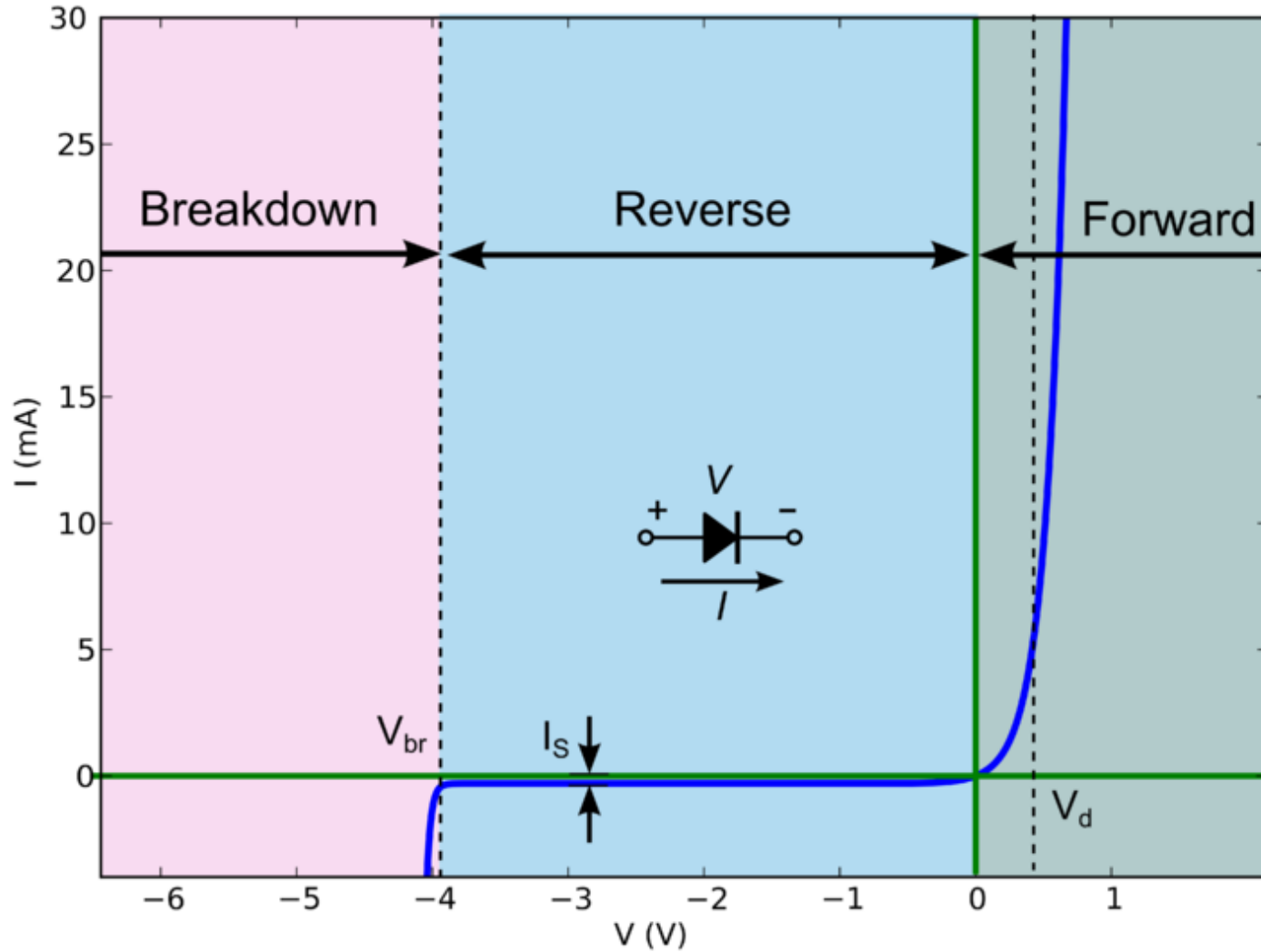
- Reverse Bias



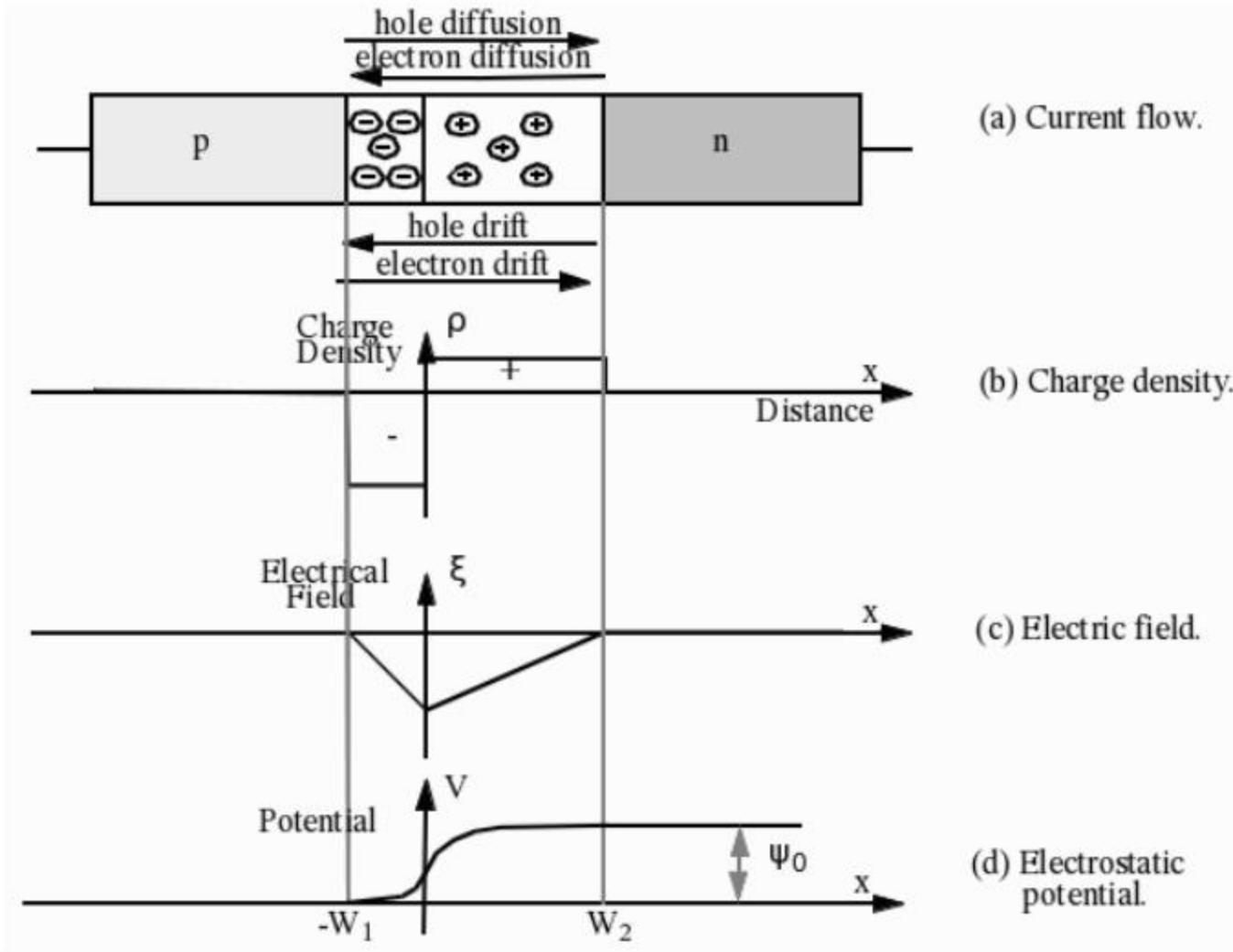
- Forward Bias



Diode



Diode



Built-in Potential

Depletion Region Width

$$\Phi_0 = \Phi_T \ln \left[\frac{N_A N_D}{n_i^2} \right]$$
$$\Phi_T = \frac{kT}{q}$$
$$W \approx \left[\frac{2\epsilon_r \epsilon_0}{q} \left(\frac{N_A + N_D}{N_A N_D} \right) \Phi_0 \right]^{\frac{1}{2}}$$

- n_i : intrinsic charge carrier concentration.
- N_x : acceptor and donor concentrations.
- k : Boltzmann constant
- T : temperature
- q : elementary charge

Diode Current

$$I_D = I_S \left(e^{\frac{V_D}{\phi_T}} - 1 \right)$$

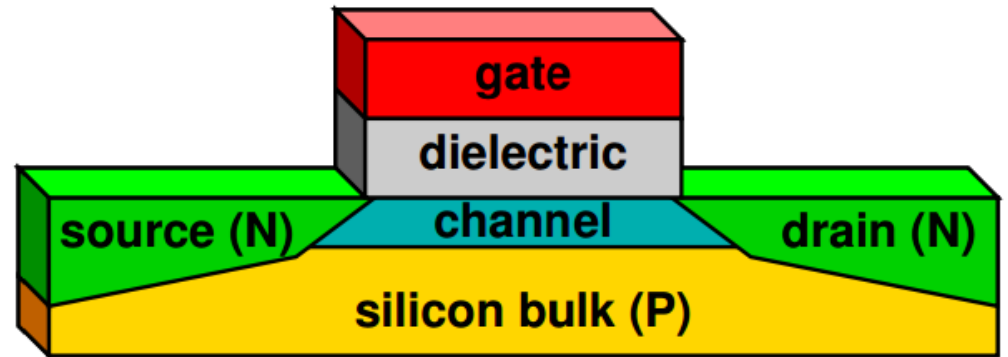
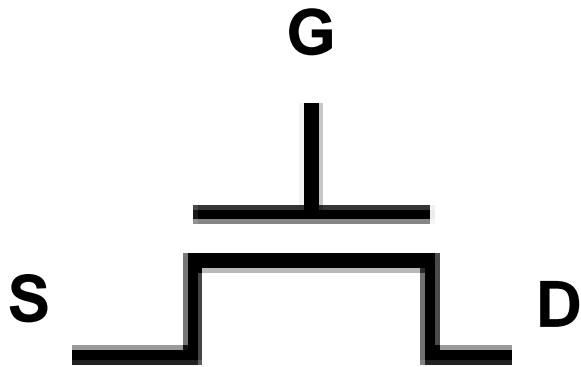
- I_D : diode current
- V_D : diode voltage
- I_S : saturation current constant
- $\phi_T = \frac{kT}{q}$: thermal voltage
 - k : Boltzmann constant
 - T : temperature
 - q : elementary charge

Diffusion capacitance

$$C_{J0} = A_D \sqrt{\frac{\epsilon_{Si} q}{2} \frac{N_A N_D}{N_A + N_D} \frac{1}{\phi_0}}$$

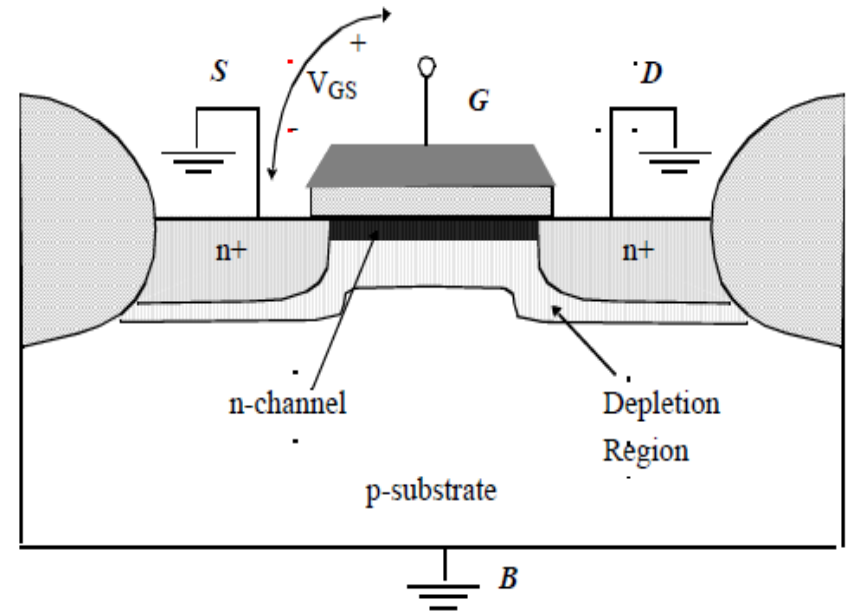
- A_D : area of diode
- ϵ_{Si} : permittivity of silicon
- N_X : carrier density
- $\phi_0 = \phi_T \ln \frac{N_A N_D}{n_i^2}$
 - $\phi_T = \frac{kT}{q}$
 - n_i : intrinsic carrier concentration

NMOS

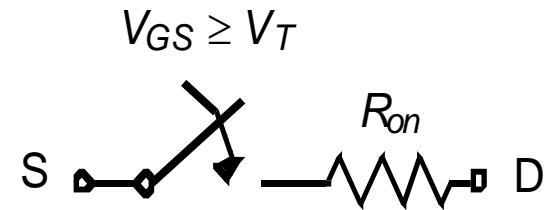


Threshold Voltage

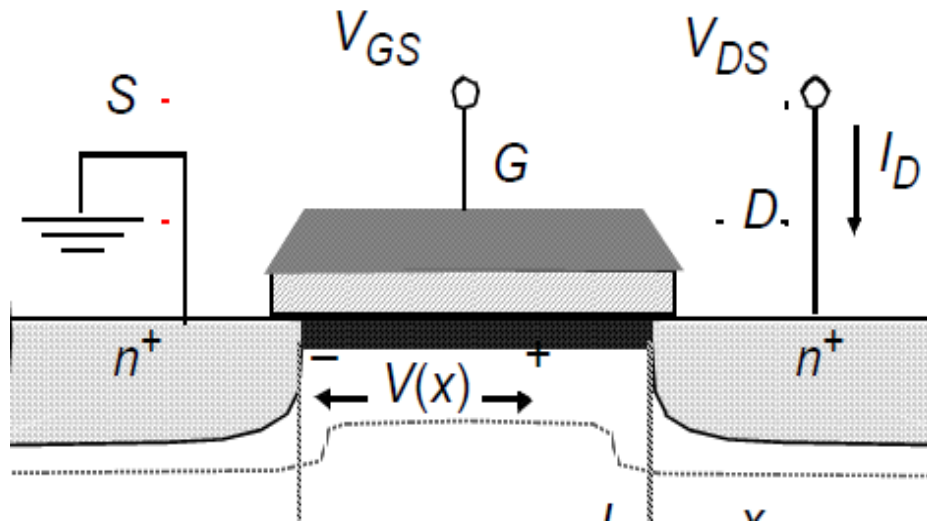
- $0 < V_{GS} < V_T$
 - Repel mobile holes and accumulation of electron beneath the gate oxide



- $V_{GS} > V_T$
 - Surface is as strongly n-type as the substrate is p-type



Operation Regions – Linear (lab 2)



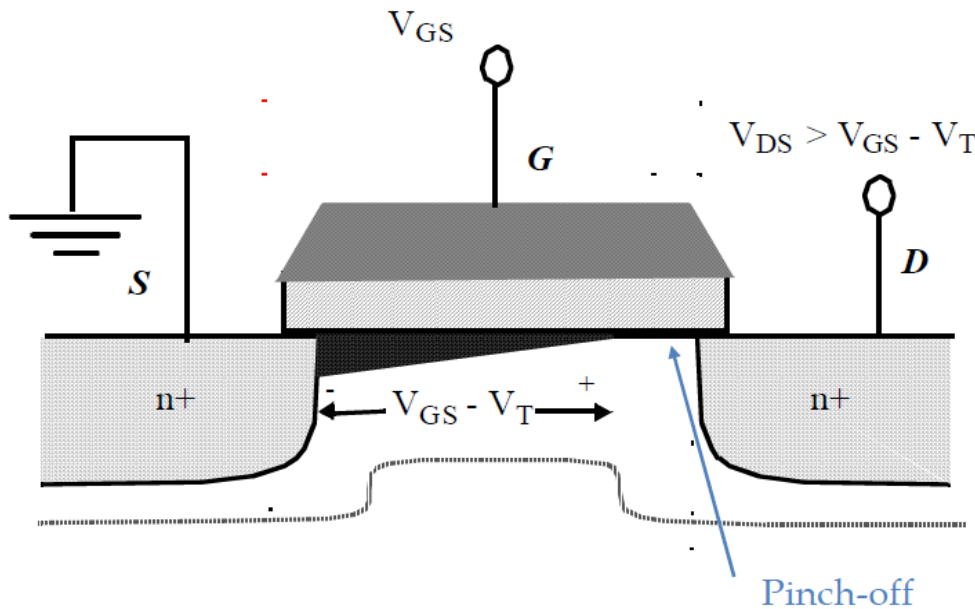
1. $V_{GS} > V_T$
2. $V_{GS} - V_T > V_{DS}$

$$I_D = k'_n \frac{W}{L} \left((V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right)$$

3. Linear contribution of V_{GT} to I_D
4. $k'_n = \mu_n C_{ox}$

In case of a P-type MOSFET, the inequalities used above should be directed opposite

Operation Regions – Saturation (lab 2)



1. $V_{GS} > V_T$
2. $V_{GS} - V_T \leq V_{DS}$

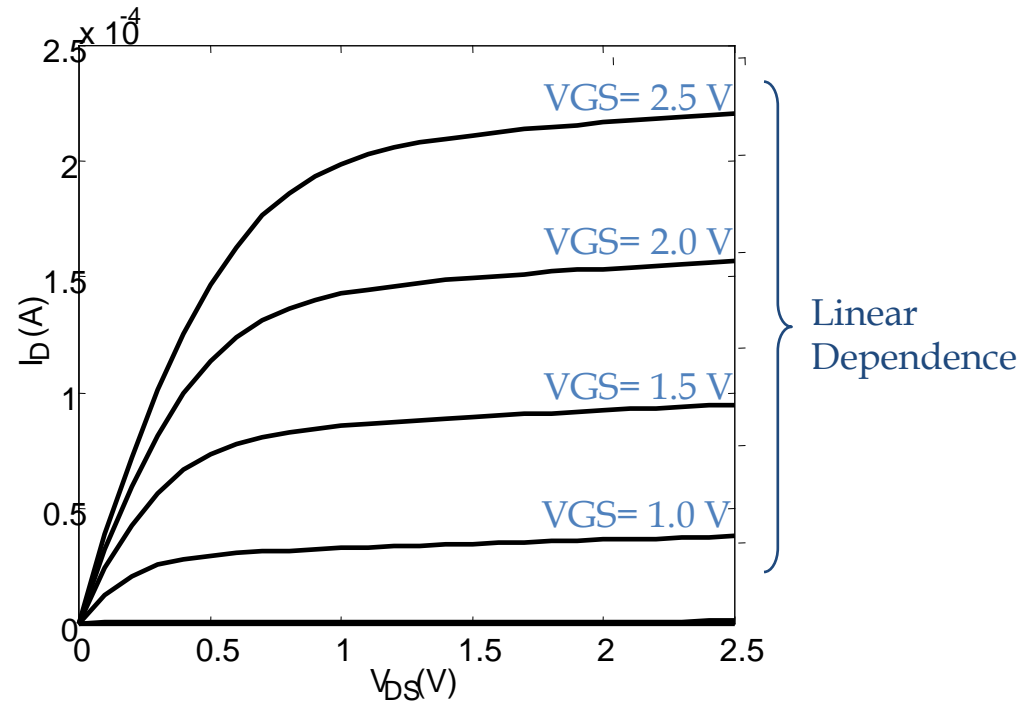
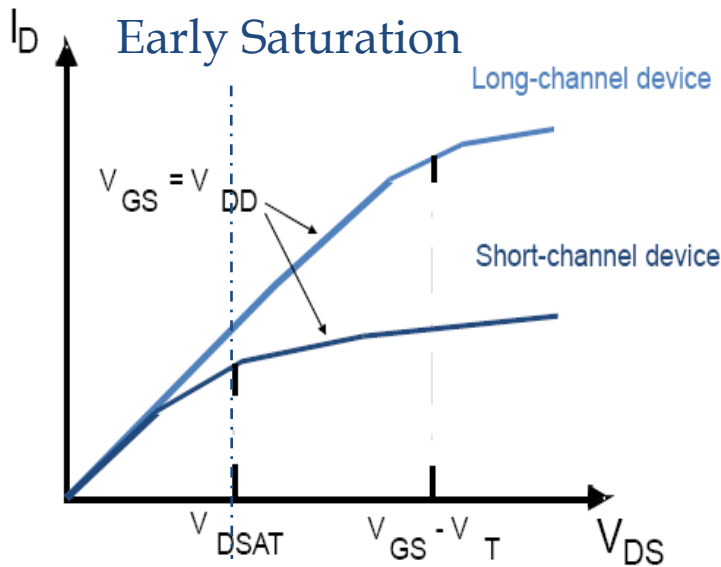
$$I_D = \frac{k'_n W}{2 L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

3. Quadratic contribution of V_{GT} to I_D
4. λ channel-length modulation parameter

In case of a P-type MOSFET, the inequalities used above should be directed opposite

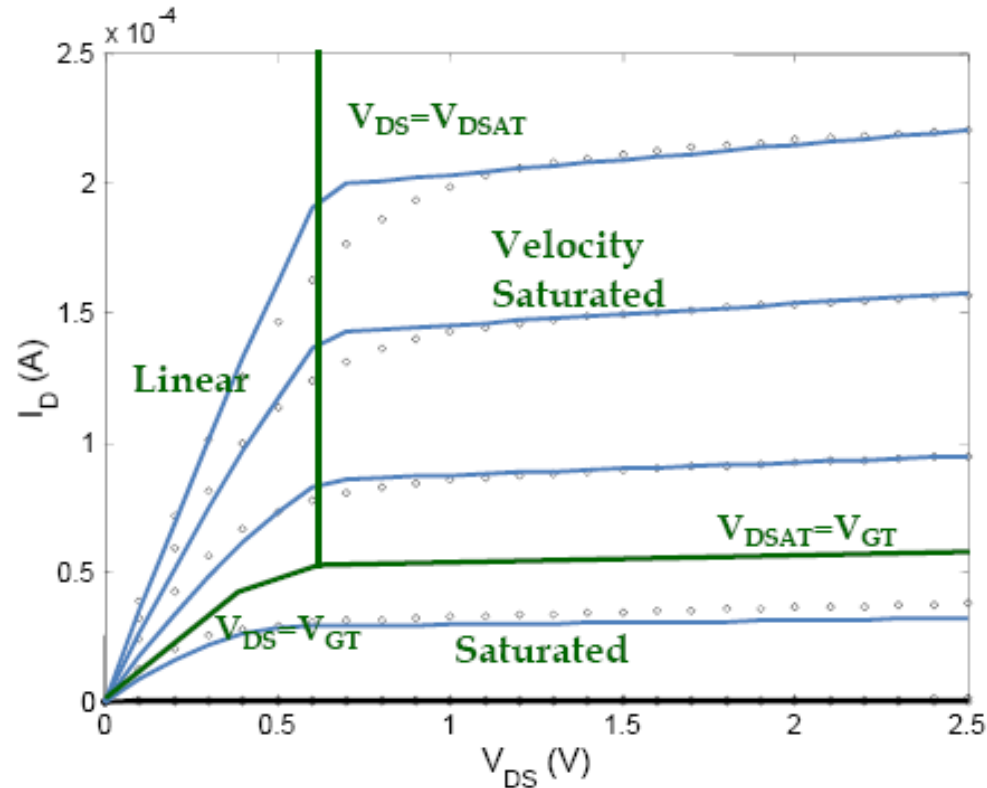
Operation Regions – Velocity Saturated

Short Channel Effects



Strong electric field causes carrier mobility degradation
: Compared to feature scaling, voltage scaling is lagging behind

A unified model



$$I_D = 0 \text{ for } V_{GT} \leq 0$$

$$I_D = k' \frac{W}{L} \left(V_{GT} V_{min} - \frac{V_{min}^2}{2} \right) (1 + \lambda V_{DS}) \text{ for } V_{GT} \geq 0$$

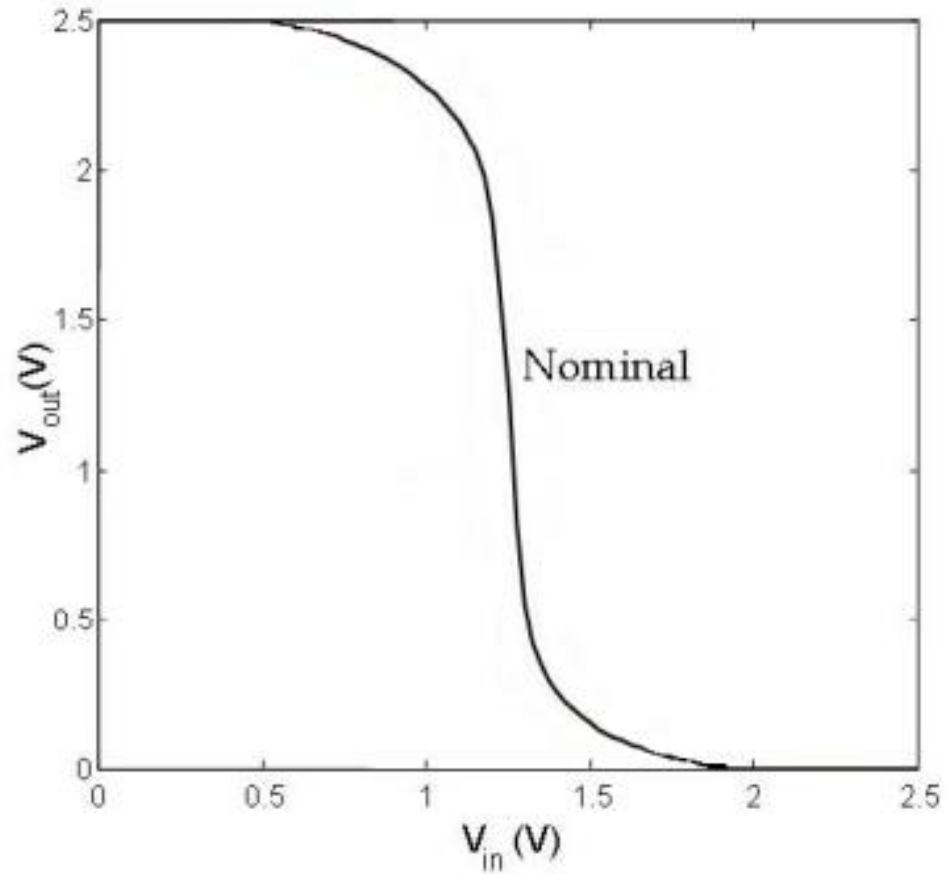
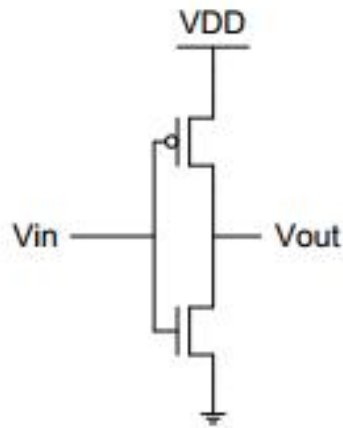
$$\text{with } V_{min} = \min(V_{GT}, V_{DS}, V_{DSAT}),$$

$$V_{GT} = V_{GS} - V_T,$$

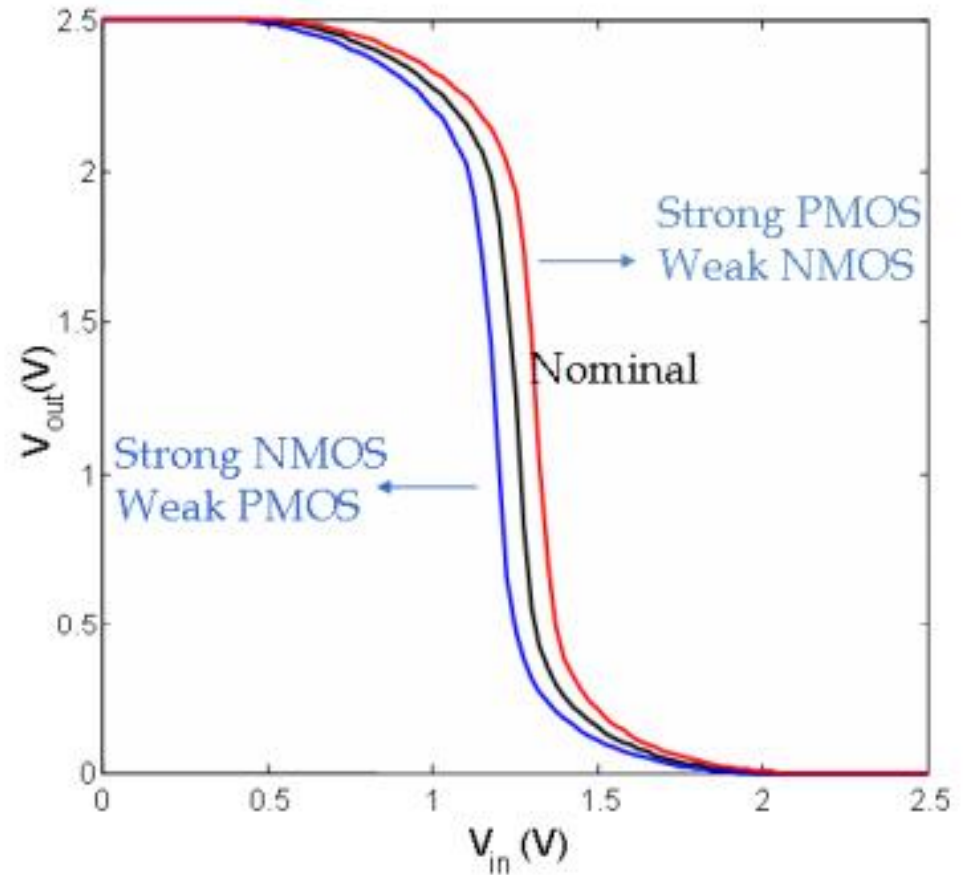
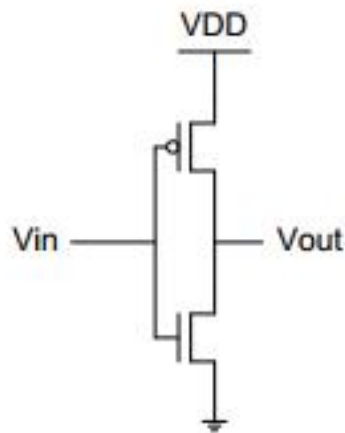
$$\text{and } V_T = V_{T0} + \gamma (\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

1. If V_{DS} is minimum:
Linear region
2. If V_{GT} is minimum:
Saturation Region
3. If V_{DSAT} is minimum :
Velocity saturated region

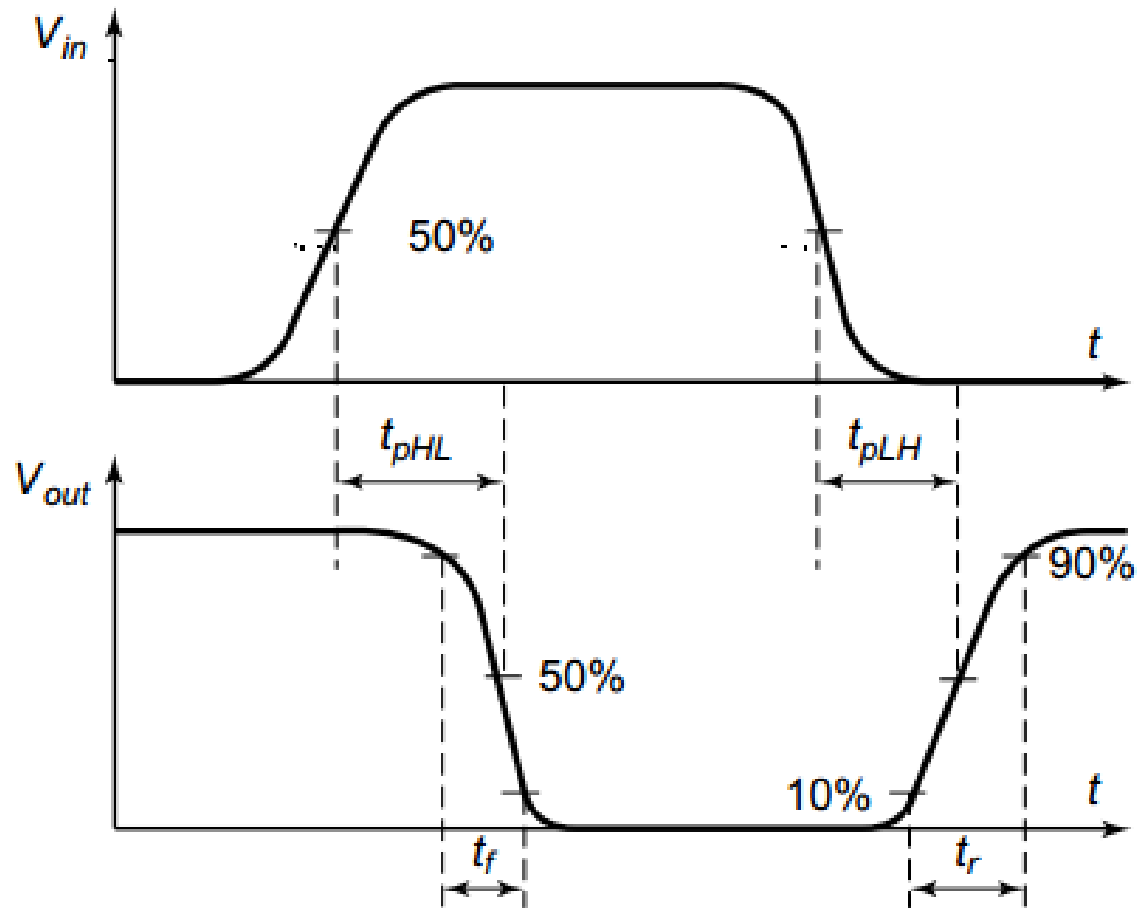
CMOS Inverter



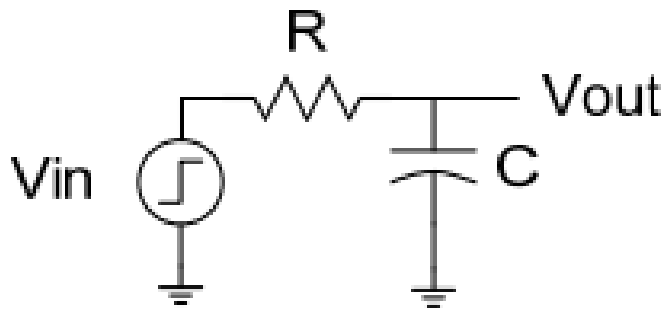
CMOS Inverter



Delay Definition



A First-Order RC Network



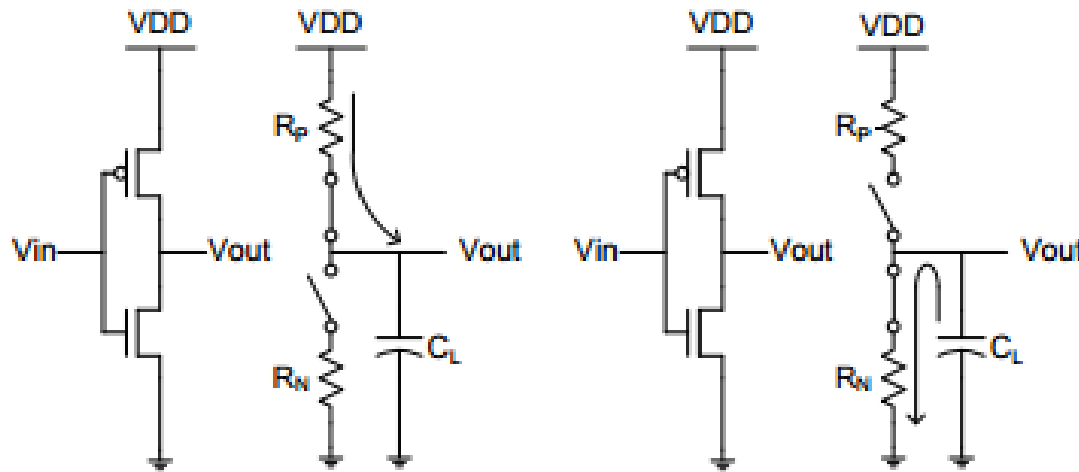
$$V_{out}(t) = (1 - e^{-t/\tau})V$$

$$\tau = R \times C$$

$$t_p = \ln(2)\tau = 0.69R \times C$$

50% voltage

CMOS Inverter: Transient Response



$$V_{in} = 0$$

(a) Low-to-high

$$V_{in} = V_{DD}$$

(b) High-to-low

$$t_{pHL} = f(R_N \times C_L)$$

$$t_{pHL} = 0.69 R_N \times C_L$$

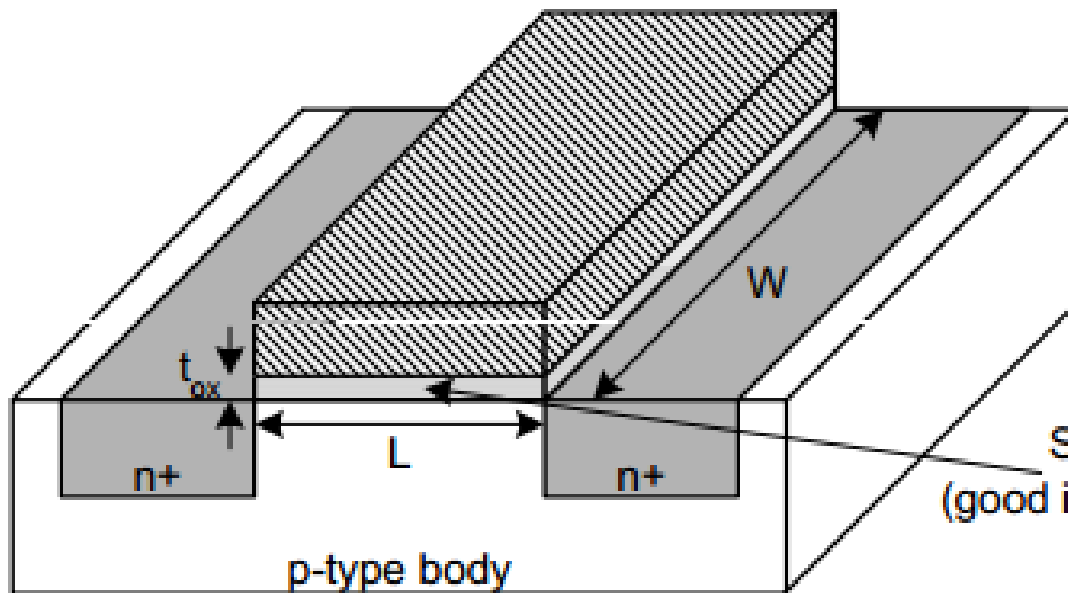
$$t_{pLH} = 0.69 R_P \times C_L$$

Capacitance

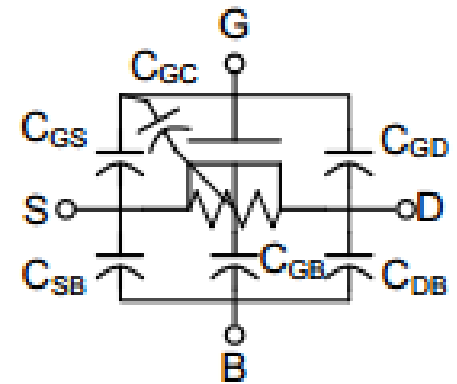
- Any two conductors separated by an insulator have capacitance
- Gate to channel capacitor is very important
 - Creates channel charge necessary for operation
- Source and drain have capacitance to body
 - Across reverse-biased diodes
 - Called diffusion capacitance because it is associated with source/drain diffusion

Gate Capacitance

- Gate capacitance can be complex, but we will use a simple model
- $C_{GC} = \epsilon_{ox} WL/t_{ox} = C_{ox} WL = C_{per_micron} W$

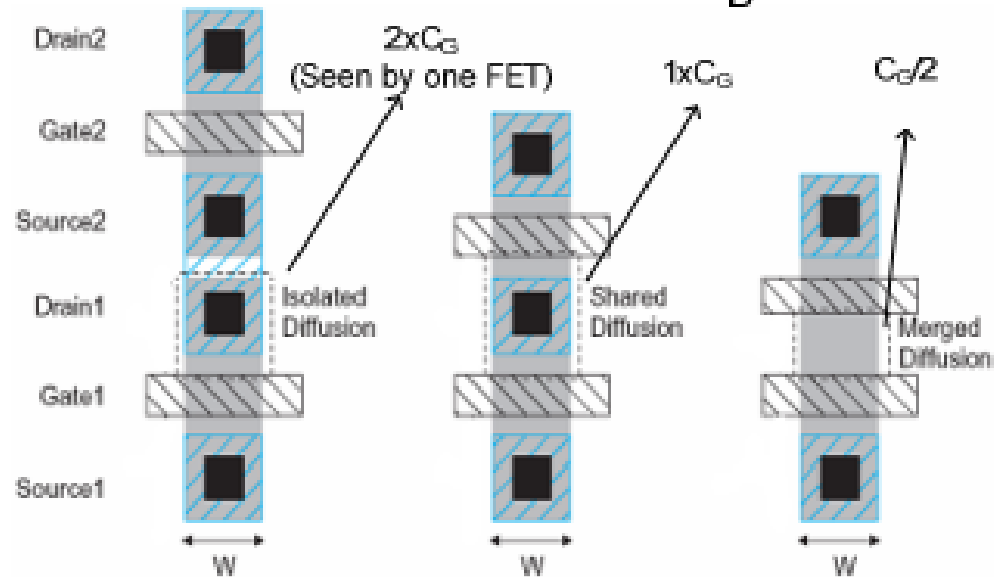
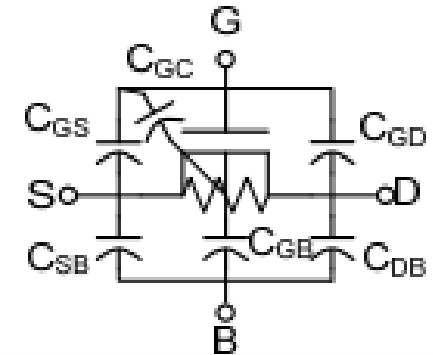


SiO₂ gate oxide
(good insulator, $\epsilon_{ox} = 3.9\epsilon_0$)



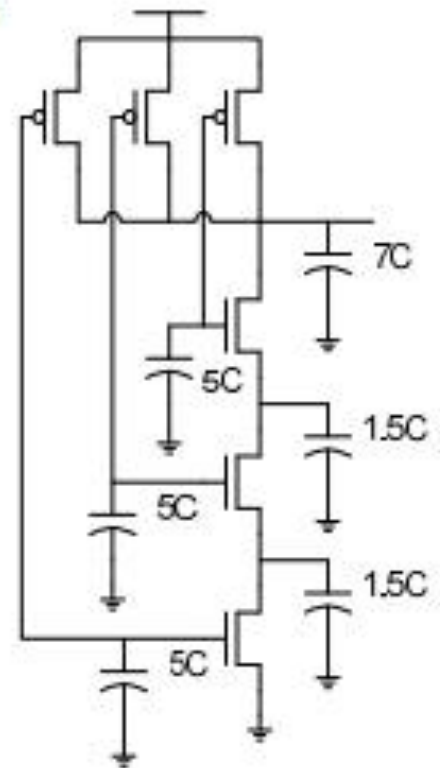
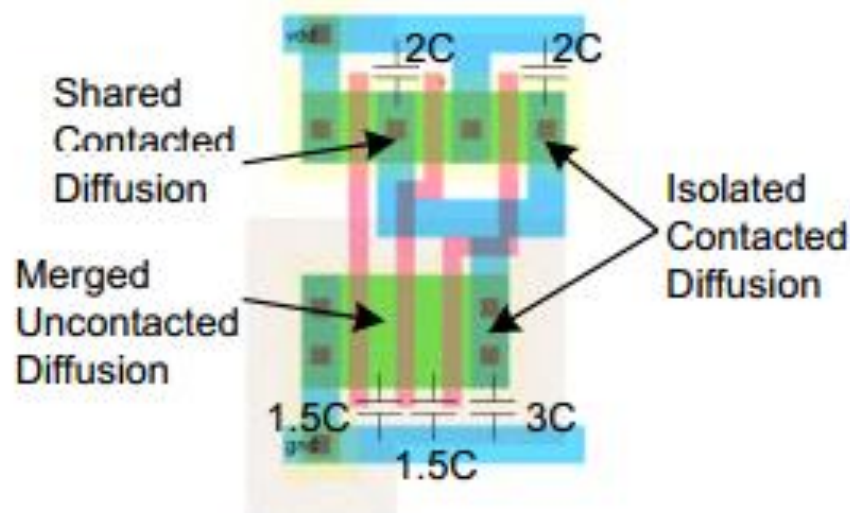
Diffusion Capacitance

- C_{SB} , C_{DB}
- Undesirable, called *parasitic* capacitance
- Capacitance depends on area and perimeter
 - Use small diffusion nodes
 - Comparable to C_G for contacted diff
 - $\frac{1}{2} C_G$ for uncontacted
 - Varies with process



Diffusion Capacitance: Example

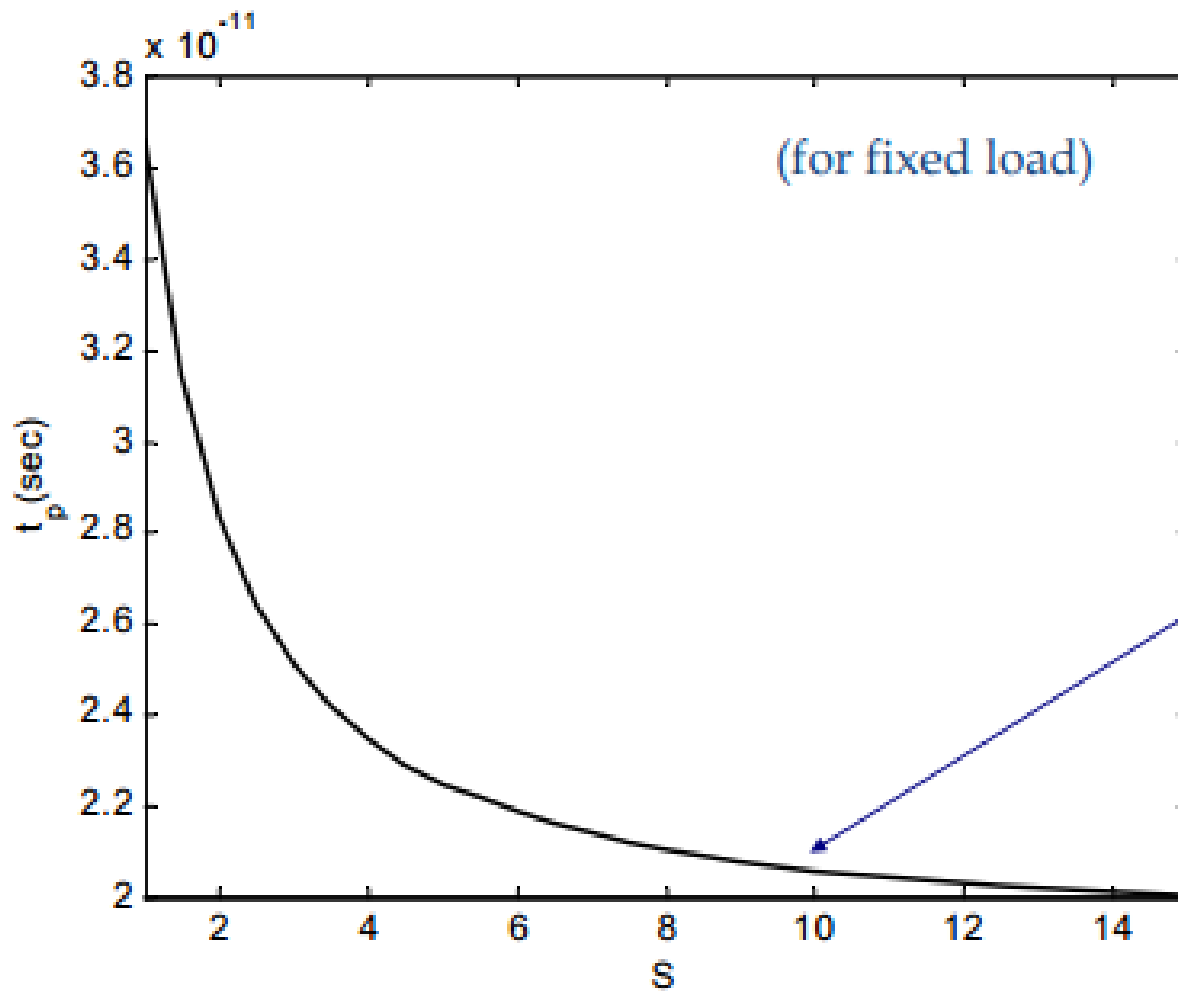
- Easiest to assume a contacted diffusion on every source/drain
- BUT: Good layout minimizes diffusion area
- Ex: NAND3 layout shares one diffusion contact
 - Reduces output capacitance by $2C$
 - Merged uncontacted diffusion helps also



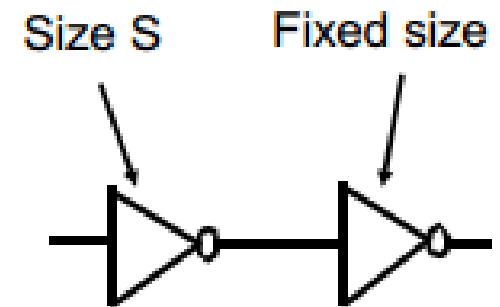
Design for Performance

- Keep capacitances small – lower C
 - Compact layout, good placement (short wires & no diffusion routing)
- Increase transistor sizes – lower R
 - Watch out for self-loading! – parasitic C increases!
- Increase V_{DD}
 - Not usually possible due to reliability and power penalties

Device Sizing

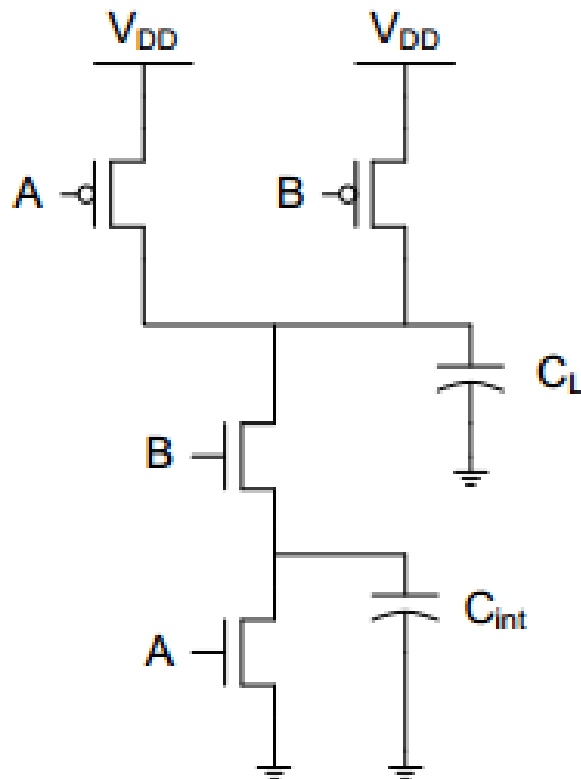


$$S = W_p/W_{p_min} = W_n/W_{n_min}$$



Increasing device width
Leads to self-loading:
Intrinsic capacitances
dominate

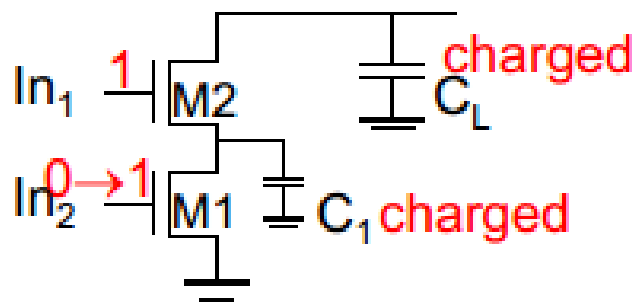
Input Pattern Effects on Delay



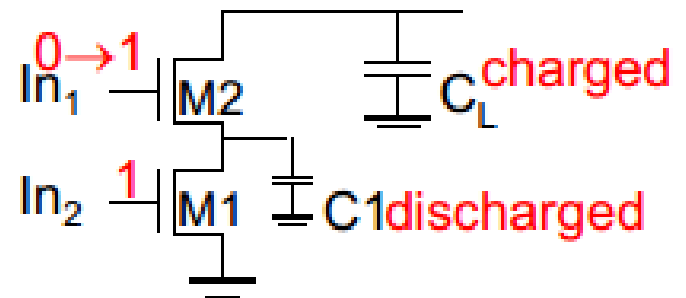
- Delay is dependent on the **pattern** of inputs
- *Ignore C_{int} for the moment!*
- Low to high transition
 - both inputs go low
 - delay is $0.69 R_p/2 C_L$
 - one input goes low
 - delay is $0.69 R_p C_L$
- High to low transition
 - both inputs go high
 - delay is $0.69 2R_n C_L$

Fast Complex Gates: Design Techniques

- Transistor Ordering

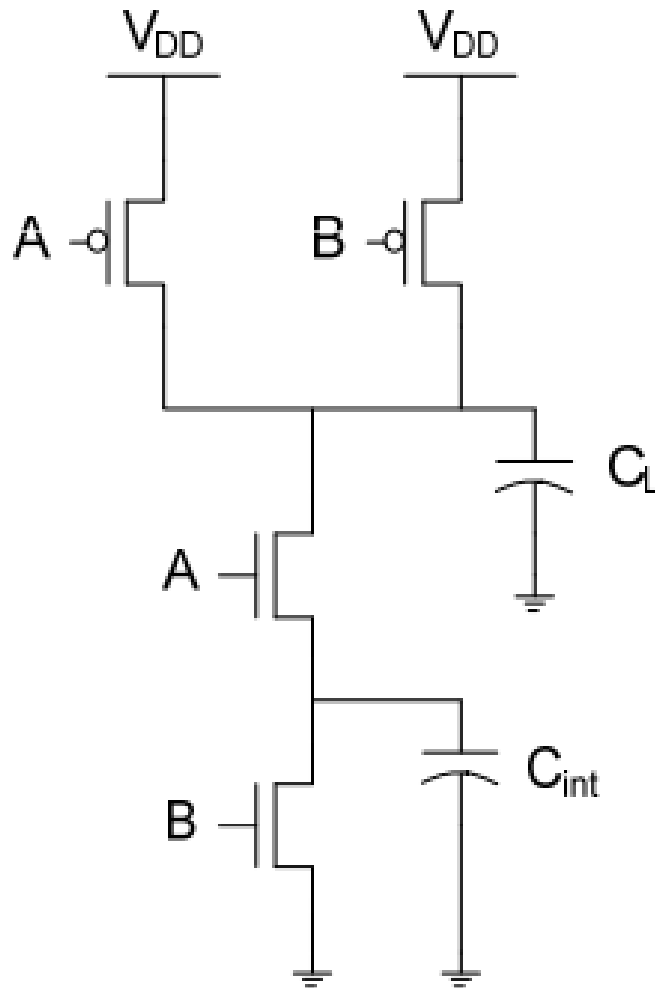


delay determined by time to discharge C_L , C_1



delay determined by time to discharge C_L

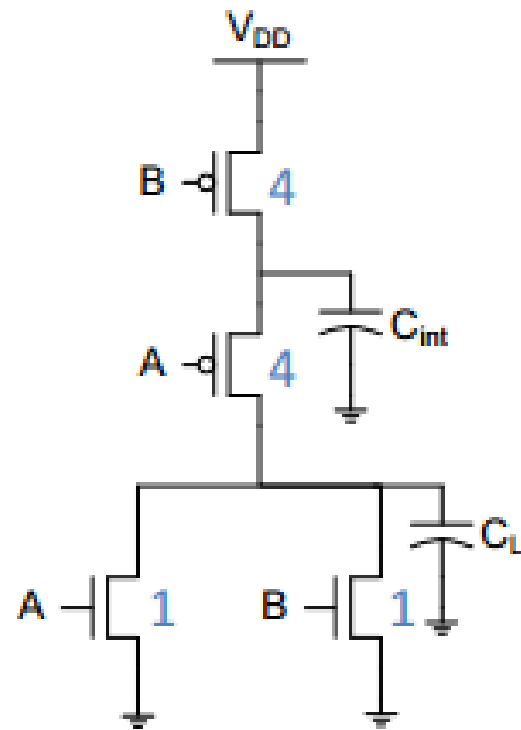
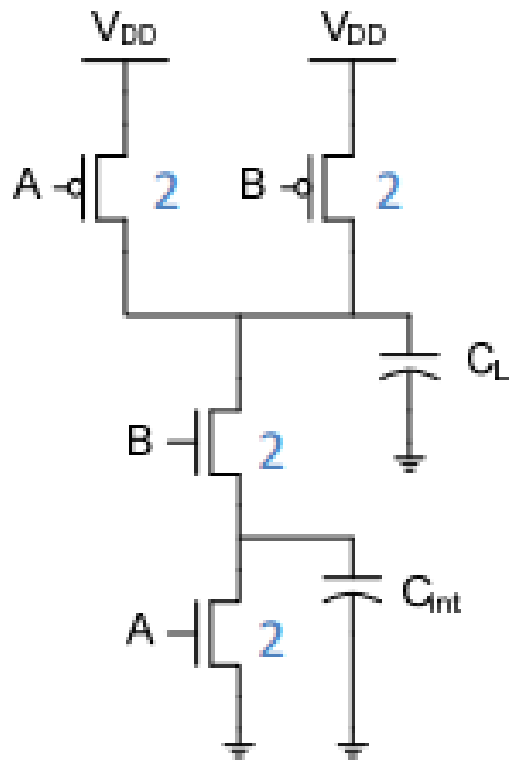
Delay Dependence on Input Patterns



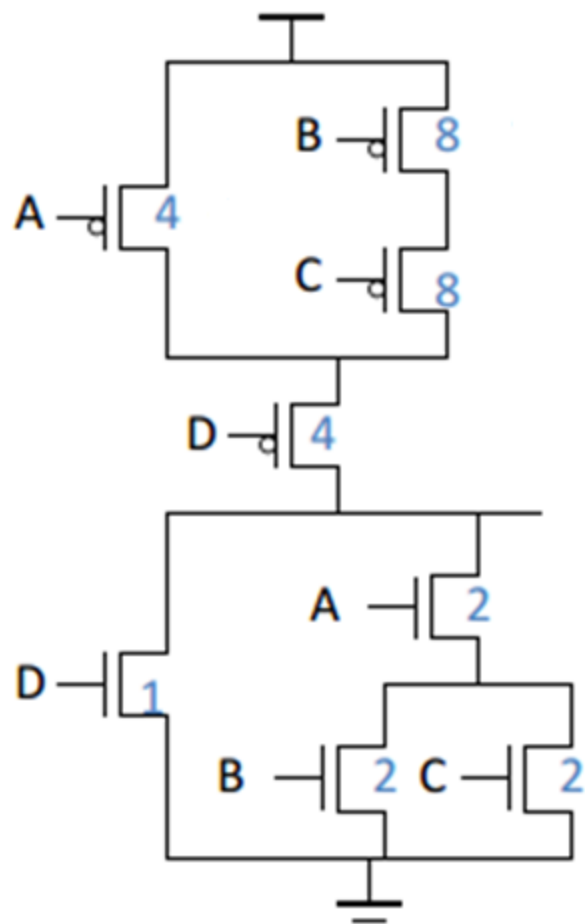
Input Data Pattern	Delay (psec)
A=B=0→1	69
A=1, B=0→1	62
A=0→1, B=1	50
A=B=1→0	35
A=1, B=1→0	76
A=1→0, B=1	57

NMOS = $0.5\mu\text{m}/0.25\mu\text{m}$
PMOS = $0.75\mu\text{m}/0.25\mu\text{m}$
 $C_L = 100\text{ fF}$

Transistor Sizing



Transistor Sizing a Complex CMOS Gate



$$\text{OUT} = D + A \cdot (B + C)$$